

LIST OF REFERENCES CITED BY APPLICANT

(Use several sheets if necessary)

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APPLICANT

Maydan et al.

FILING DATE

May 24, 2001

APPLICATION NO.

09/866,172

GROUP

2874

U.S. PATENT DOCUMENTS







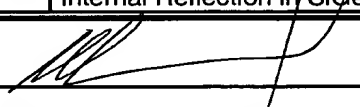
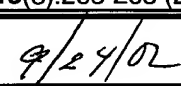
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
AA		5,194,079	03/16/93	Tumminelli et al.	65	3.110	02/04/92
AB		5,599,397	02/04/97	Anderson et al.	118	728	03/27/96
AC		5,108,792	04/28/92	Anderson et al.	427	248.1	03/09/90

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)

AD	Y. Zuoya et al., "The Effects of Composition on the Spectral Loss Characteristics of SiGe Planar Waveguide Structures", Mat. Res. Soc. Symp. Proc. 281:461-465 (1993).
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<p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</p>		

